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Large Mirrors and Telescopes

Wenhan Jiang
Roland Geyl
Myung K. Cho
Fan Wu
Editors

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Contents

vii	<i>Conference Committee</i>
ix	<i>Symposium Committees</i>
xi	<i>Introduction</i>

PLENARY SESSION

7281 02	Evolution of wavelength shrinkage in lithography [7281-01] M. Kameyama, Nikon Corp. (Japan); M. McCallum, Nikon Precision Europe GmbH (United Kingdom); S. Owa, Nikon Corp. (Japan)
---------	---

SESSION 1-1

7281 03	Four decades of ZERODUR mirror substrates for astronomy [7281-02] T. Döhring, R. Jedamzik, T. Westerhoff, P. Hartmann, SCHOTT AG (Germany)
7281 04	Study on the surface of large-aperture optical elements in frequency domain [7281-03] S. Li, R. Zhang, Sichuan Univ. (China)
7281 05	Novel method of phasing segmented mirrors [7281-04] Q. Zhu, S. Wang, G. Cao, Beijing Institute of Technology (China)
7281 06	Influence of optical surface error on scattering loss of optical mirror [7281-05] D. Wu, Y. Dai, G. Wang, National Univ. of Defense Technology (China)
7281 07	Control system for multi-motor friction drive of a large-scale optical telescope [7281-06] Y. Mao, Institute of Optics and Electronics (China) and Graduate School of the Chinese Academy of Sciences (China); J.-G. Ma, Q. Bao, Institute of Optics and Electronics (China); S. Yang, Southwest Univ. (China)
7281 08	FEM analysis and experiment study of an ultrathin active mirror [7281-07] Y. Ni, P. Guo, Q. Huang, J. Yu, Soochow Univ. (China)
7281 09	Subaperture stitching interferometer for large optics [7281-08] S. Zeng, Y. Dai, S. Chen, National Univ. of Defense Technology (China)
7281 0A	Figure analysis and adjustment of a large aperture reflector [7281-09] X. L. Chen, N. J. Ruan, J. Ma, Y. Su, Beijing Institute of Space Mechanics and Electricity (China)

SESSION 1-2

- 7281 0B **Analysis of the deforming and moving feature when using stressed lap on both convex and concave hyperboloids** [7281-10]
B. Gao, Nanjing Institute of Astronomical Optics & Technology (China); F. Wu, Institute of Optics and Electronics (China)
- 7281 0C **Decoupling control for position error and surface error of segmented primary mirror** [7281-11]
B. Dong, X. Yu, X. Zhang, X. Wang, Beijing Institute of Technology (China)
- 7281 0D **Optimizing attaching area in an ultrathin active mirror system** [7281-12]
B. Xie, Y. Ni, Soochow Univ. (China)
- 7281 0E **Observer-based higher order sliding mode control for large optical astronomical telescopes** [7281-13]
W. Zhou, X. Ye, W. Guo, Nanjing Univ. of Information Science & Technology (China); Z. Wu, Graduate School of the Chinese Academy of Sciences (China)
- 7281 0F **Acceleration feedback control for low velocity friction in a servo control system** [7281-14]
T. Tang, Institute of Optics and Electronics (China) and Graduate School of the Chinese Academy of Sciences (China); Y. Huang, C. Fu, J. Ma, Institute of Optics and Electronics (China)
- 7281 0G **Aberration analysis for development of a large-aperture reflector by finite element** [7281-15]
Y. Peng, Nanjing Institute of Astronomical Optics and Technology (China) and Graduate School of the Chinese Academy of Sciences (China); L. Yuan, Nanjing Institute of Astronomical Optics and Technology (China)
- 7281 0H **Analysis of piston error of an optical sparse-aperture imaging system** [7281-16]
J. Zhao, D. Wang, Z. Zhou, Y. Wan, Z. Jiang, S. Tao, Beijing Univ. of Technology (China)
- 7281 0I **Forward kinematic analysis on the parallel supporting structure of large opto-electronic equipment** [7281-17]
G. Cheng, S.-R. Ge, China Univ. of Mining and Technology (China); Y.-J. Wan, Institute of Optics and Electronics (China)

POSTER SESSION

- 7281 0J **Research on the structure and dynamic characteristics of a fast-steering mirror** [7281-18]
J. Zhou, H. Yin, East China Jiaotong Univ. (China); Y. Wang, Beijing Institute of Space Mechanics and Electricity (China)
- 7281 0K **Numerical simulation of airflow in a 2m telescope** [7281-19]
F. Zhao, Beijing Technology and Business Univ. (China); P. Wang, Beijing Institute of Technology (China); Y. Gong, L. Zhang, C. Meng, J. Lin, Beijing Technology and Business Univ. (China)

- 7281 OL **The mathematical analysis when using four-bar linkage structure to off-axis segment** [7281-20]
B. Gao, Nanjing Institute of Astronomical Optics & Technology (China); F. Wu, Institute of Optics and Electronics (China)
- 7281 OM **Optical design of a reflecting telescope with a large field** [7281-21]
D. Gong, Changchun Institute of Optics, Fine Mechanics and Physics (China) and Graduate School of the Chinese Academy of Sciences (China); H. Wang, T. Tian, Changchun Institute of Optics, Fine Mechanics and Physics (China); J. Yuan, Changchun Office of Shenyang Army Branch (China)
- 7281 ON **Study on the limiting ability of shaping aspheric surfaces by FEM** [7281-22]
C. Zeng, J. Yu, Soochow Univ. (China)
- 7281 OO **Fabrication and testing of a 600mm diameter brazing SiC mirror** [7281-23]
B. Zhang, X. Wang, Changchun Institute of Optics, Fine Mechanics and Physics (China) and Graduate School of the Chinese Academy of Sciences (China); X. K. Wang, Z. Zhang, X. Zhang, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 7281 OP **Method for detection of primary mirror figure deformation in space** [7281-24]
X. Wang, H. Mao, D. Zhao, Beijing Institute of Technology (China)
- 7281 OQ **Orientation error analysis of an alt-alt photoelectric telescope** [7281-25]
X. Han, Changchun Institute of Optics, Fine Mechanics and Physics (China) and Graduate School of the Chinese Academy of Sciences (China); J. Zhang, J. Zhao, Changchun Institute of Optics, Fine Mechanics and Physics (China); Y. Zhao, Changchun Institute of Optics, Fine Mechanics and Physics (China) and Graduate School of the Chinese Academy of Sciences (China); X. Wu, Z. Wang, Changchun Institute of Optics, Fine Mechanics and Physics (China)
- 7281 OR **Diffraction effects on image quality of a segmented mirror with quasi-annulus sector** [7281-26]
Y. Wen, J. Yan, B. Wang, M. Xiao, Beijing Institute of Technology (China)
- 7281 OS **Hybrid algorithm in phase diversity wavefront sensing** [7281-27]
X. Wang, D. Zhao, H. Mao, X. Wang, Beijing Institute of Technology (China)
- 7281 OT **Application of adaptive optics to a space-ground large deployable optics system** [7281-28]
X. Zhang, X. Yu, J. Yan, B. Dong, Y. Huang, X. Wang, Beijing Institute of Technology (China)
- 7281 OU **Real-time orbit prediction in a large telescope system** [7281-29]
S. Yang, Southwest Univ. (China); Y. Mao, Institute of Optics and Electronics (China) and Graduate School of the Chinese Academy of Sciences (China); J. Ma, Institute of Optics and Electronics (China)
- 7281 OV **Inverse kinematic analysis of parallel supporting structure based on Rodrigues parameters** [7281-30]
G. Cheng, S.-R. Ge, China Univ. of Mining and Technology (China); Y.-J. Wan, Institute of Optics and Electronics (China)

- 7281 OW **Research on cooling technology for a large-aperture solar telescope's primary mirror** [7281-31]
Q. Wang, Nanjing Institute of Astronomical Optics and Technology (China) and Graduate School of the Chinese Academy of Sciences (China); H. Zhang, Nanjing Institute of Astronomical Optics and Technology (China)
- 7281 OX **Far-infrared Fizeau interferometer for a large aspheric mirror** [7281-32]
Y. Wu, Y. Zhang, Institute of Optics and Electronics (China)

Author Index

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Introduction

Optical manufacturing technology has achieved tremendous progress, especially during the last 20 years both in China and abroad. To meet the demand of the development in this area, AOMATT-International Symposium on Advanced Optical Manufacturing and Testing Technology has been held four times from 2000 to 2008. The 4th International Symposium on Advanced Optical Manufacturing and Testing Technology (AOMATT08) was held at Wang Jiang Hotel in Chengdu, China, 19–21 November 2008. A total of 381 papers have been selected for publication in the Proceedings of SPIE volumes 7281, 7282, 7283 and 7284, corresponding to the four conferences of AOMATT08: Large Mirrors and Telescopes; Advanced Optical Manufacturing Technologies; Optical Test and Measurement Technology and Equipment; and Design, Manufacturing, and Testing of Micro- and Nano-Optical Devices and Systems. We have faced many challenges during the organization of AOMATT08. They include the big Sichuan Wenchuan earthquake on 12 May 2008, the worldwide financial crisis, and the deepening recession in many countries around the world. These challenges and difficulties have negatively impacted the number of papers and attendees for AOMATT08. The number of accepted papers decreased from 485 for AOMATT07 to 381 for AOMATT08. However, conference quality has continued to improve. Based on comments from authors and attendees, significant improvements have been made in conference organization, the opening ceremony, quality of the plenary presentation, oral presentations, workshops, and the closing ceremony, etc. A more important fact is the continued improvement in the quality of the papers published in the Proceedings of SPIE. Many papers report cutting-edge research and development; more authors are from famous universities, research institutions, and leading enterprises around the world. Authors and attendees had the opportunity to exchange ideas and learn from each other at the conference.

We are delighted that each AOMATT symposium is more successful than the previous one. It has become a well-established symposium covering advanced optical manufacturing and testing technologies, and has attracted a loyal following in academy and industries around the world. Our goal is to develop AOMATT into a must-attend international symposium for the optical manufacturing and testing community. We would like to express our sincere appreciation to COS—The Chinese Optical Society, IOE—Institute of Optics and Electronics, Chinese Academy of Sciences, and to SPIE for sponsoring AOMATT08. We want to thank authors and attendees for attending the symposium and sharing their research with their colleagues around the world. We especially thank IOE and Dr. Yudong Zhang, President of IOE, for hosting AOMATT08 and the tremendous hospitality during the conference.

The world is in the middle of significant financial and economic crisis. Crisis often brings difficulties and opportunities at the same time. Many countries have

announced economic stimulus measures. The Chinese government has promised 600 billion Yuan RMB to six key national projects. Several projects are closely related to optical manufacturing and testing technology and equipments and represent opportunities for researchers and enterprises around the world. New discoveries and products will emerge as a result. We are looking forward to seeing you all at the AOMATT 2010 in China, please watch the SPIE and IOE websites for call for papers and exact time and locations.

Li Yang

Secretary General, AOMATT 2008

Chairman, Committee on Optical Manufacturing Technology (COMT), COS